1FW/762

## **PATENT**

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Das et al.

Serial No.: 10/045,542

Filed: October 26, 2001

Confirmation No.: 3570 Group Art Unit: 1762

Examiner: Michael. E. Barr

METHOD OF FABRICATING AN OXIDE LAYER ON A SILICON CARBIDE

LAYER UTILIZING AN ANNEAL IN A HYDROGEN ENVIRONMENT

Date: July 7, 2004

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## SUBSTITUTE AMENDMENT

Sir:

Applicants provide the present Substitute Amendment in response to the Notice of Non-Compliant Amendment mailed June 29, 2004 and to address the issues raised in the Official Action mailed March 2, 2004. Applicants have conformed the present Substitute Amendment as requested in the Notice of Non-Compliant Amendment and, therefore, request entry of the present Substitute Amendment.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 6 of this paper.